Form PTO-1449 (REV. 8-83) U.S. Department of Commerce Patent and Trademark Office	Atty. Docket: 0492611-0510 (MIT 10443),	In re Application No. 10/669,883
INFORMATION DISCLOSURE STATEMENT *(Use several sheets if necessary)*	Applicant: Manalis, et al.	
	Filing Date: September 23, 2003	Group:

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Examiner's Initials	U.S. Patent No.	Applicant	Issue Date	Class	Subclass

U.S. PATENT APPLICATIONS

Examiner's Initials:	Publication Number:	Applicant:	Publication Date:	Group:	Art Unit:
N	2004/0038426	Manalis	February 26, 2004	\	

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				Yes	No

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Examiner's Initials	Citation (Including Author, Title, Date, Pertinent Pages, Etc.)

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